AMENDMENTS TO THE CLAIMS

Please amend claim 1 and 7 as follows:

1. (Currently Amended)A content addressable memory (CAM) having a plurality of <u>6T</u> ternary memory cells in a fabricated semiconductor material, each ternary half cell comprising:

an equal number of transistors of a p-type and an n-type, the p-type transistors being formed in a n-well region and the n-type transistors being formed in a p-well region of said semiconductor material, the p-wells being separated from the n-wells [having] by at most one p+ to n+ region spacing, the transistors being interconnected to form said half ternary CAM cell and wherein the interconnections between the half cell are restricted to a first group of conductive layers and connections between said cell and signal lines external to said cell are formed in a second group of conductive layers.

- 2. (original)A CAM as defined in claim 1, said external signal lines including a search line, matchline, bitline and word line.
- 3. (original)A CAM as defined in claim 2, said search line being formed in a third metal layer.
- 4. (original)A CAM as defined in claim 3, said matchline and wordline being formed in a fourth metal layer.
- 5. (original)A CAM as defined in claim 1, said bit line being formed in a fifth metal layer.
- 6. (original)A CAM as defined in claim 1, said silicon layer including one polysilicon layer.
- 7. (Currently Amended)A content addressable memory (CAM), comprising:
- (a) a plurality of <u>6T</u> half ternary CAM cells each having an equal number of transistors of a p-type and an n-type, the p-type transistors being formed in a first well region and the n-type transistors being formed in a second well region of a semiconductor material, the <u>p-wells being separated from the n-wells [having] by</u> at most one p+ to n+ region spacing, the transistors being interconnected to form said half ternary CAM cell and wherein the interconnections are restricted to a silicon layer and a first metal layer;
- (b) power lines formed in a second metal layer and coupled to said cells;
- (c) a plurality of search lines formed in a third metal layer;
- (d) a plurality of wordlines and matchlines formed in a fourth metal layer; and
- (e) a plurality of bitlines formed in a fifth metal layer.



